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PATENT
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IN THE UNITED STATES PATENT AND TRADEMARK OFFICE
TECHNICAL CENTER 2800

In re application of:
Norikazu MIZUNO, et al.

Serial No: 09/670,917

Filed: September 29, 2000

For: SEMICONDUCTOR DEVICE
MANUFACTURING METHOD AND
APPARATUS FOR REMOVING SILICON
NITRIDE FORMED IN A REACTION
CONTAINER WITH NF_3 GAS FLOWING
INTO THE REACTION CONTAINER (AS
TWICE AMENDED)

Art Unit: 2822

Examiner: Maria F. Guerrero

I hereby certify that this correspondence
is being deposited with the United States
Postal Service with sufficient postage as
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Commissioner for Patents
Washington D.C. 20231, on

April 21, 2003

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Diane Zynn

Name

Diane Zynn

04/21/03

Signature

Date

PETITION FOR EXTENSION OF TIME

Box RCE
Commissioner for Patents
Washington, D.C. 20231

Dear Sir:

In accordance with 37 C.F.R. 1.136, Applicant respectfully petitions the
Commissioner for a three-month extension of time extending to April 22, 2003, the period
for response to the Final Office Action dated October 22, 2002. Please charge the fee of
\$930 for this extension to Deposit Account No. 50-1314. The responsive paper(s) are
attached.

Please charge any insufficiency or credit any overpayment to Deposit Account
No. 50-1314. A copy of this petition is enclosed.

Respectfully submitted,

HOGAN & HARTSON L.L.P.

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02 FC:1253 930.00 CH

Date: April 21, 2003

By: *Ying Chen*

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Registration No. 50,193

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